

## ABSTRACT OF THE DISCLOSURE

5 A force sensing element is provided with a gauge  
portion and a plurality of electrodes. The gauge portion  
is formed of an n-type semiconductor substrate whose  
(100)-face serves as a main face, a p-type semiconductor  
substrate whose (110)-face serves as a main face, or a p-  
type semiconductor substrate whose (111)-face serves as a  
main face, and is pressed in a thickness direction of the  
10 semiconductor substrate upon receiving a force. The  
electrodes are electrically connected to the gauge  
portion such that a current path extending in a direction  
corresponding to the thickness direction of the  
semiconductor substrate is formed in the gauge portion.  
15 The force sensing element thus constructed makes it  
possible to detect a force with high precision.